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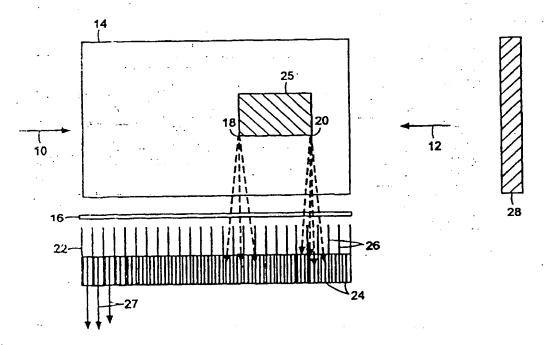
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НИИГПЭ

ФОНД ЭКСПЕРТОВ

(54) Title: SIDE SCATTER TOMOGRAPHY SYSTEM



### (57) Abstract

An X-ray tomography system measures X-ray side-scattered (18) by material (25) concealed within an enveloping surface (14). One or more X-ray beams (10, 12) are incident on the enveloping surface and scattered onto collimated detectors (24) disposed in arrays parallel to the incident X-ray beams. By varying the relative orientation of the enveloping surface with respect to the X-ray beams and measuring the X-ray side-scattered by the material concealed within the enveloping surface, the shape, density, position and composition of the contexts of the enveloping surface may be mapped.